Search Notes			

Application/Control No.	Applicant(s)/Patent under Reexamination	
10/705,884	SHIRAISHI ET AL.	
Examiner	Art Unit	
Paul D. Kim	3729	

SEARCHED			
Class	Subclass	Date	Examiner
29	25.35 603.04 603.06 603.07	8/19/2005	PK
156	64 307.1 37 9		
360	294.4 294.6	V	

INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)		
	DATE	EXMR
Reviewed Parent Application 09/933,774 (US PAT. 6,690,551)	8/19/2005	РК
Text Search EAST/NPL (IEEE)	8/19/2005	PK
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